



PATENT
790001-2002

2813

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Yoshitaka TSUNASHIMA et al.
Serial No. : 09/803,265
Filed : March 9, 2001
For : **SEMICONDUCTOR DEVICE HAVING A GATE INSULATING
FILM STRUCTURE INCLUDING AN INSULATING FILM
CONTAINING METAL, SILICON AND OXYGEN AND
MANUFACTURING METHOD THEREOF**
Examiner : Jennifer M. Dolan
Group Art Unit : 2813

6/2
J. Steptoe
3-2-03

745 Fifth Avenue
New York, New York 10151

I hereby certify that this correspondence is being deposited with
the United States Postal Service as first class mail in an envelope
addressed to: Assistant Commissioner for Patents, Washington,
DC 20231, on February 17, 2003.

Grace L. Pan, Reg. No. 39,440

Name of Applicants, Assignee or Registered Representative


Signature

February 18, 2003

Date of Signature

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TECHNOLOGY CENTER 2800

AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

This is in response to the Office Action mailed on November 18, 2002, which sets
a three-month response period. Please amend this application as follows: